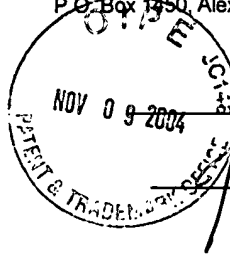


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

James M. Helt

Serial No. 10/821,403

Filing Date: April 8, 2004

For FABRICATION OF NANOSTRUCTURES

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) Examiner To Be Assigned
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INFORMATION DISCLOSURE STATEMENT

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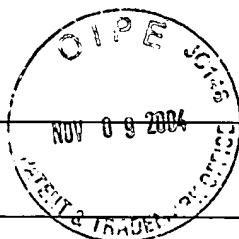
Dear Sir:

In accordance with the provisions of 37 C.F.R. § 1.56, Applicants request that citation and examination of the references identified on the attached form PTO-1449, required copies of which are enclosed herewith in accordance with 37 C.F.R. § 1.98, be made during the course of examination of the above-referenced application for United States Letters Patent. References A1 and A5-A8 were cited in the International Search Report dated September 14, 2004 for corresponding PCT Patent Application No. PCT/US2004/010932. A Copy of the Search Reports is attached.

Respectfully submitted,

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Form PTO-1449 (Rev. 8-88)	Attorney Docket No. CMD01-001-US	Serial No. 10/821,403
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	Applicant: James M. Helt	
	Filing Date: April 8, 2004	Group: 1733

U.S. PATENT DOCUMENTS

Examiner Initials*		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	A1	6,326,058	12/2001	Biebuyck, et al.			
	A2	5,669,303	09/1997	Maracas, et al.			
	A3	2002/0119251	08/2002	Chen, et al.			
	A4	2002/0050220	05/2002	Schueller, et al.			

FOREIGN PATENT DOCUMENTS

Examiner Initials*		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	A5	WO03/059804	07/2003	WO				X
	A6	WO01/89788	11/2001	WO				

OTHER ITEMS - NON PATENT LITERATURE DOCUMENTS

Include, as applicable: Author, Title, Date, Publisher, Edition or Volume, Pertinent Pages

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	A7	Helt, J.M., et al. "A Benchtop Method for the Fabrication and Patterning of Nanoscale Structures on Polymers", J. AM. Chem. Soc., 2004, Vol. 126, pp. 628-634.
	A8	Stark, R.W., et al., "Microfluidic Etching Driven by Capillary Forces for Rapid Prototyping of Gold Structures", Microelectronic Engineering, 2003, 67-68, pp. 229-236.
	A9	Ng, W.K., et al., "Microcontact Printing of Catalytic Nanoparticles for Selective Electroless Deposition of Metals on Nonplanar Polymeric Substrates", Applied Physics Letter, Vol. 81, No. 16, pp. 3097-3099, 2002.
	A10	Bamber, M.J., et al., "Accurate Determination of Young's Modulus and Poisson's Ratio of Thin Films by a Combination of Acoustic Microscopy and Nanoindentation", Thin Solid Films, 398-399, pp. 299-305, 2001.
	A11	deGennes, P.G., Wetting - Statics and Dynamics. Reviews of Modern Physics, 1985. 57(3): p. 827-863.
	A12	Du, B., et al., "Study of Elastic Modulus and Yield Strength of Polymer Thin Films Using Atomic Force Microscopy", Langmuir, 17, 11, pp. 3286-3291, 2001.
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	A14	Johnson, K.L., et al., "Contact Mechanics", Cambridge University Press, pp. 84-106, 136-144, 153-179; 1987.

Examiner	Date Considered
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

A15	Johnson, K.L., Continuum mechanics modeling of adhesion and friction. <i>Langmuir</i> , 1996. 12(19): p. 4510-4513.
A16	Janssen, G.C.A.M., J.F. Jongste, and A.H. Verbruggen, Deformation mechanism in the forcefill process. <i>Journal of Applied Physics</i> , 2000. 87(2): p. 889-892.
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A18	Fan, C.F., Yielding of a model glassy polycarbonate under tension – a molecular mechanics simulation. <i>Macromolecules</i> , 1995. 28(15): p. 5215-5224.
A19	Alblas, J.B. and M. Kuipers, Contact problems of a rectangular block on an elastic layer of finite thickness - Part I: The thin layer. <i>Acta Mechanica</i> , 1970. 8(3-4): p. 133-145.
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